NIST

Technology Partnerships Office

NISTTech

FORCE-FREQUENCY MICROSCOPE AND METHOD FOR USING SAME 1ST Provisional Filing title: NANOMECHANICAL PROPERTY MEASUREMENT BY FORCE-FREQUENCY MODULATED ATOMIC FORCE MICROSCOPY (FFM-AFM)

Docket 13-026

Abstract

The AFM imaging mode proposed here is a new high speed frequency modulation techique performed in scanning controlled force AFM modes like force volume of Peak Force Trapping modes. It consists of tracking the changes in the resonance frequncy of a higher eigenmode AFM cantilever during scanning as the AFM probe intermittenly contacts the sample at a predefined applied maximum force(setpoint). The key measurements are in the form of an eigenmode cantilever resonance frequency and amplitude data sets that can be analyzed to provide quantitative information on the nanomechnaical preperties of the surface as a function of depth at each osciallation cycle or ";tap";. The resulting three dimensional insight into the nanomechnaical properties of surfaces at such a nano scale is a powerful tool in the development of nanotechnology (advanced materials, MEMS, NEMS, Micro/Nano-fabrication etc.)

Inventors

Gates, Richard S.

Status of Availability

This invention is available for licensing exclusively or non-exclusively in any field of use.

Last Modified: 08/08/2014